



In re: Application of
DAVID A. SMITH, GARY A. BARONE, MARTIN E. HIGGINS,
BRUCE R. F. KENDALL & DAVID J. LAVRICH
U.S. Patent Application
Serial Nos. 10/642,866
Filed: August 18, 2003
For: METHOD FOR CHEMICAL VAPOR DEPOSITION OF
SILICON ON TO SUBSTRATES FOR USE IN CORROSIVE
AND VACUUM ENVIRONMENTS

Art Unit: 1775 -
Attn: Examiner Robert R. Koehler

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SIR:

CERTIFICATE OF FIRST-CLASS MAILING

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited today with the United States Postal Service as first-class, postage-prepaid mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Date

4/6/05

John F. A. Earley III
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John F. A. Earley III

AUTHORIZATION TO CHARGE DEPOSIT ACCOUNT

The Commissioner is hereby authorized to charge any additional fees which may be required by this paper and during the pendency of this application to Account No. 05-0208.

Date

4/6/05

John F. A. Earley III
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AMENDMENT

This is in response to the office action dated October 6, 2004.

AMENDMENTS TO THE CLAIMS begin on page 2.

REMARKS begin on page 14.